

# Thin Films SRF 2024

11th International Workshop on Thin Films  
and New Ideas for Pushing the Limits of RF Superconductivity

Paris, September 16 – 20, 2024  
Université Paris-Saclay, France

## $\text{Nb}_3\text{Sn}/\text{Cu}$ by Magnetron Sputtering for SRF cavities at INFN-LNL

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17.09.2024



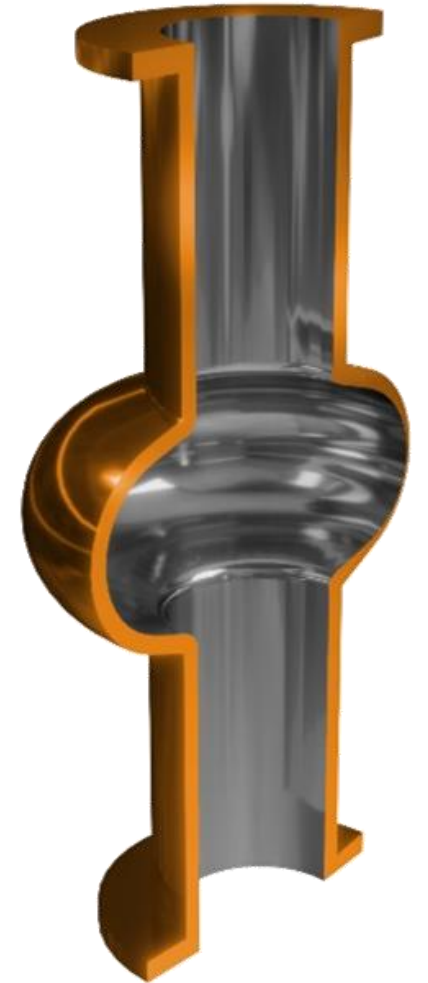
Work supported by INFN CSN5 experiment SAMARA and INFN CSN1 experiments SRF and RD\_FCC

This project has received funding from the European Union's Horizon-INFRA-2023-TECH-01 under GA No 101131435 – iSAS  
and from the European Union's Horizon 2020 Research and Innovation programme under GA No 101004730 – i.FAST



# Outline

- **Nb<sub>3</sub>Sn/Cu challenges**
- **INFN-LNL goal**
- **Deposition recipe optimization**
- **Nb<sub>3</sub>Sn R&D projects timeline**
- **Conclusion**



# Our partners



# Nb<sub>3</sub>Sn on Cu: multiple challenges

- A15 are brittle materials
- Complicated phase diagram
- **Low melting point substrate (Cu)**
- **Interface diffusion**
- **Tuning of coating parameters**
- **Substrate preparation**
- **Target production/magnetron design**
- **Trapped flux**
- **Cavity tuning**



SRF cavities  
R&D for  
FCC-ee

INFN Accelerators European  
Strategy Program



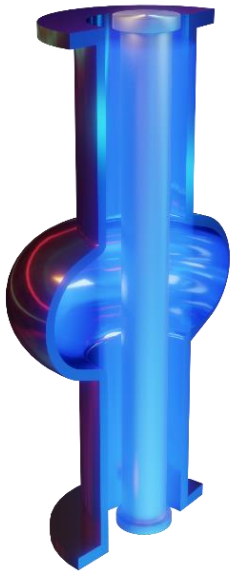
## ESPP Accelerator R&D Roadmap



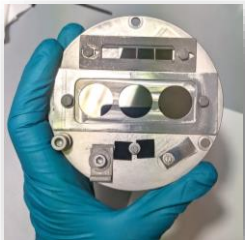
# INFN-LNL goal

## Main R&D activities

1.3 GHz elliptical  $\text{Nb}_3\text{Sn}/\text{Cu}$  prototype cavity  
How?



**DCMS** with stoichiometric single target (small samples)



**DC Magnetron Sputtering**

Easy and validated  
(e.g. LHC Nb/Cu)

**Deposition recipe must be optimised**

cylindrical target production via **LTD** (6 GHz cavities)



**Liquid Tin Diffusion**

# Deposition recipe optimization

1

**tuning of  
deposition  
parameters based  
on  $T_c$  of small film  
samples**

2

**production and  
RF test of  
quadrupole  
resonator (QPR)  
sample**

3

**apply 1&2 again for  
the deposition and  
RF test of 1.3 GHz  
prototype**



# $T_c$ -driven parameter optimization

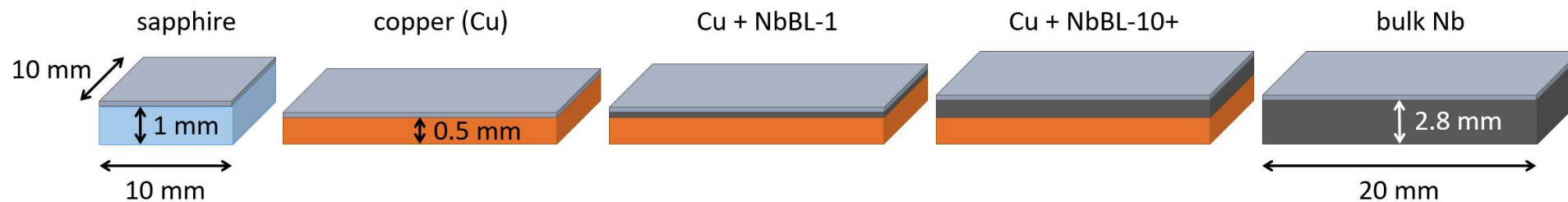
# Sample production

Tight-feedback driven standardized process:

*deposition > characterization > parameter adjustment*

Films are deposited on different substrates:

- **sapphire** for reference as substrate does not affect the film
- **copper without and with a niobium buffer layer (NbBL) of variable thickness**
- **bulk Nb**





# Deposition temperature limit

## Limited by weakening point of copper

- Cu starts weakening at ~ **450 °C** ( $\text{Nb}_3\text{Sn}$  requires > **930 °C**)
- **softening of 6 GHz cavity flanges observed at 650 °C**

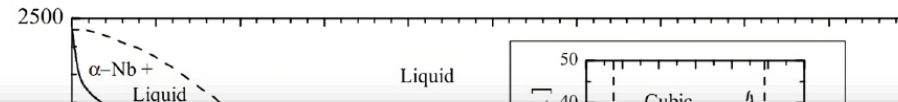
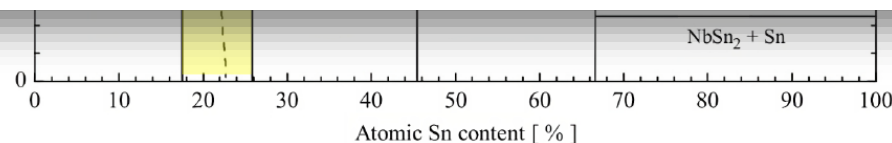
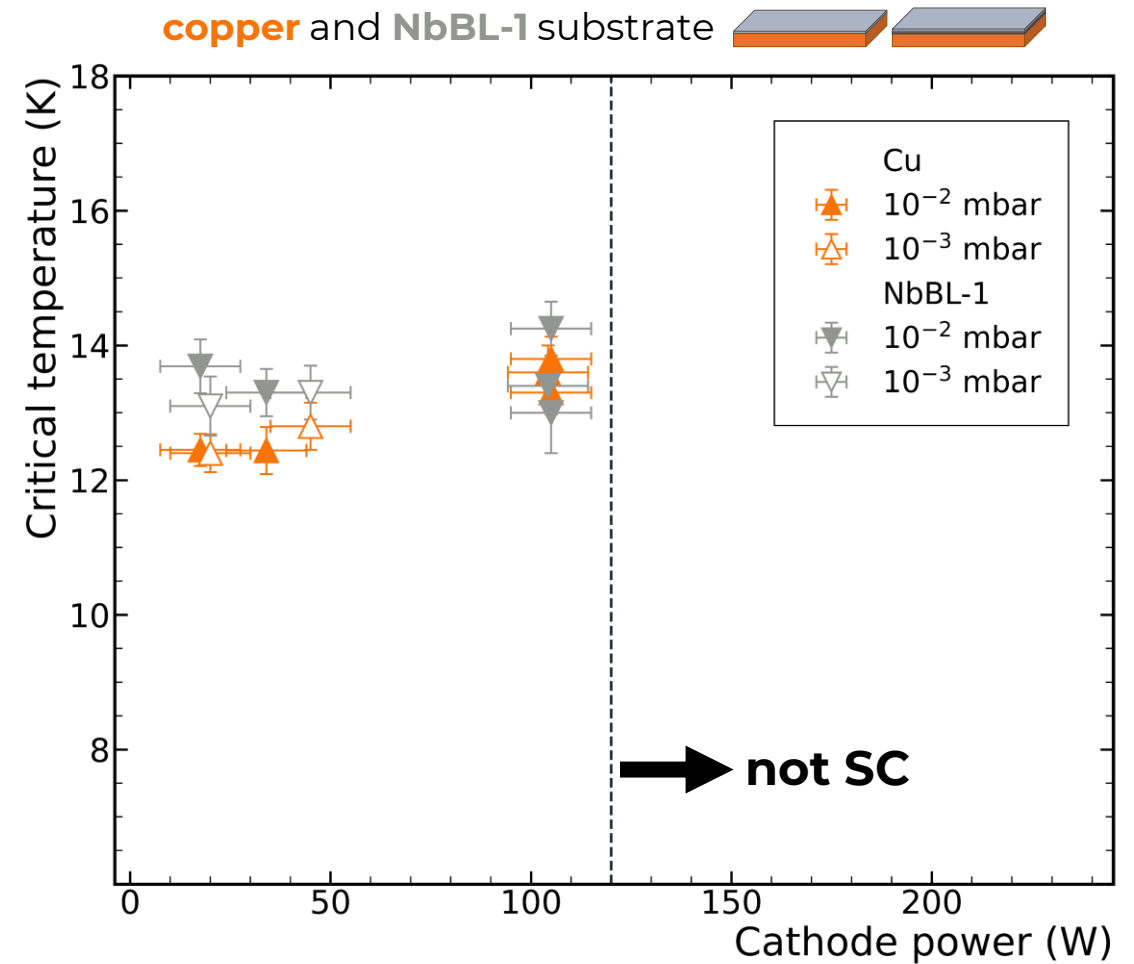
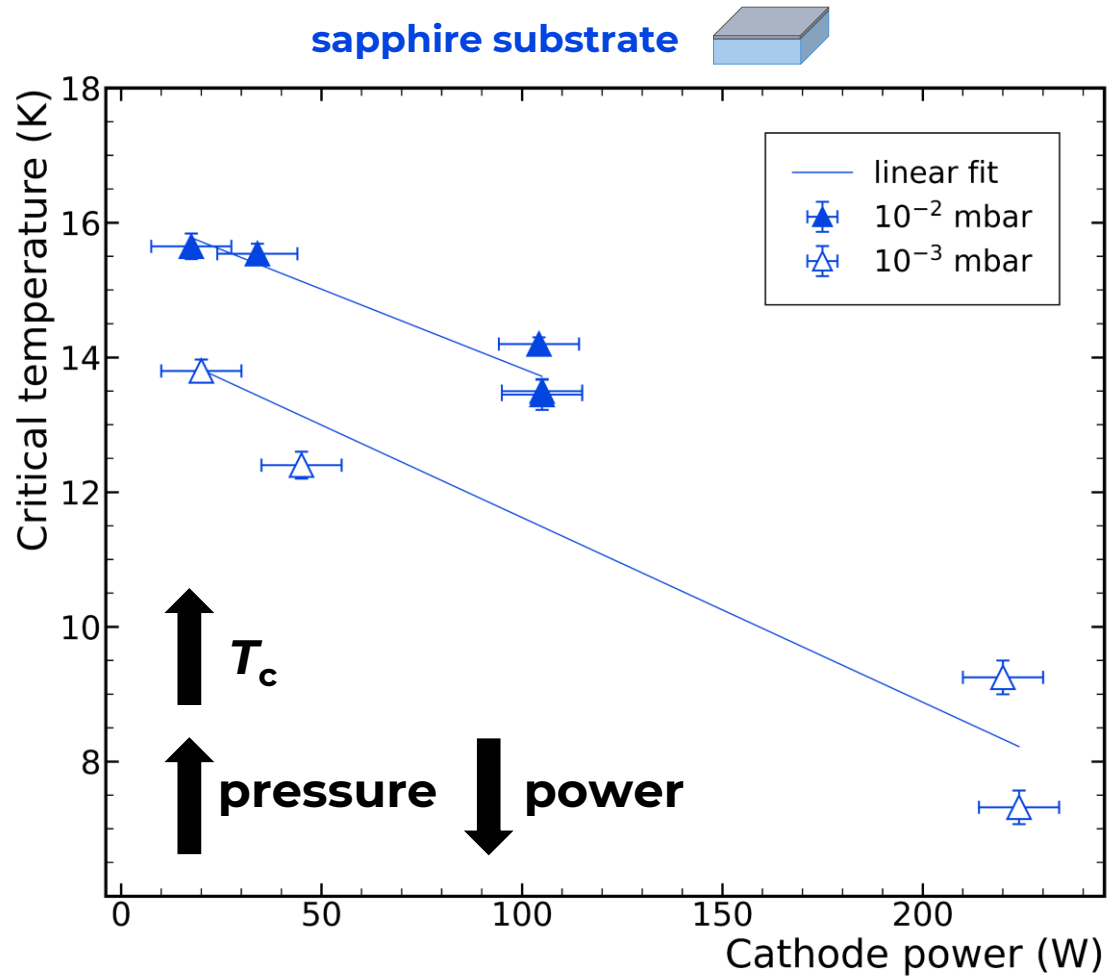


Figure 7.10 Flange deformation due to high temperature (650 °C). The copper becomes softer and lose his mechanical properties. A deformed flange is a very probable source of vacuum leaks, avoiding the possibility of the rf test.

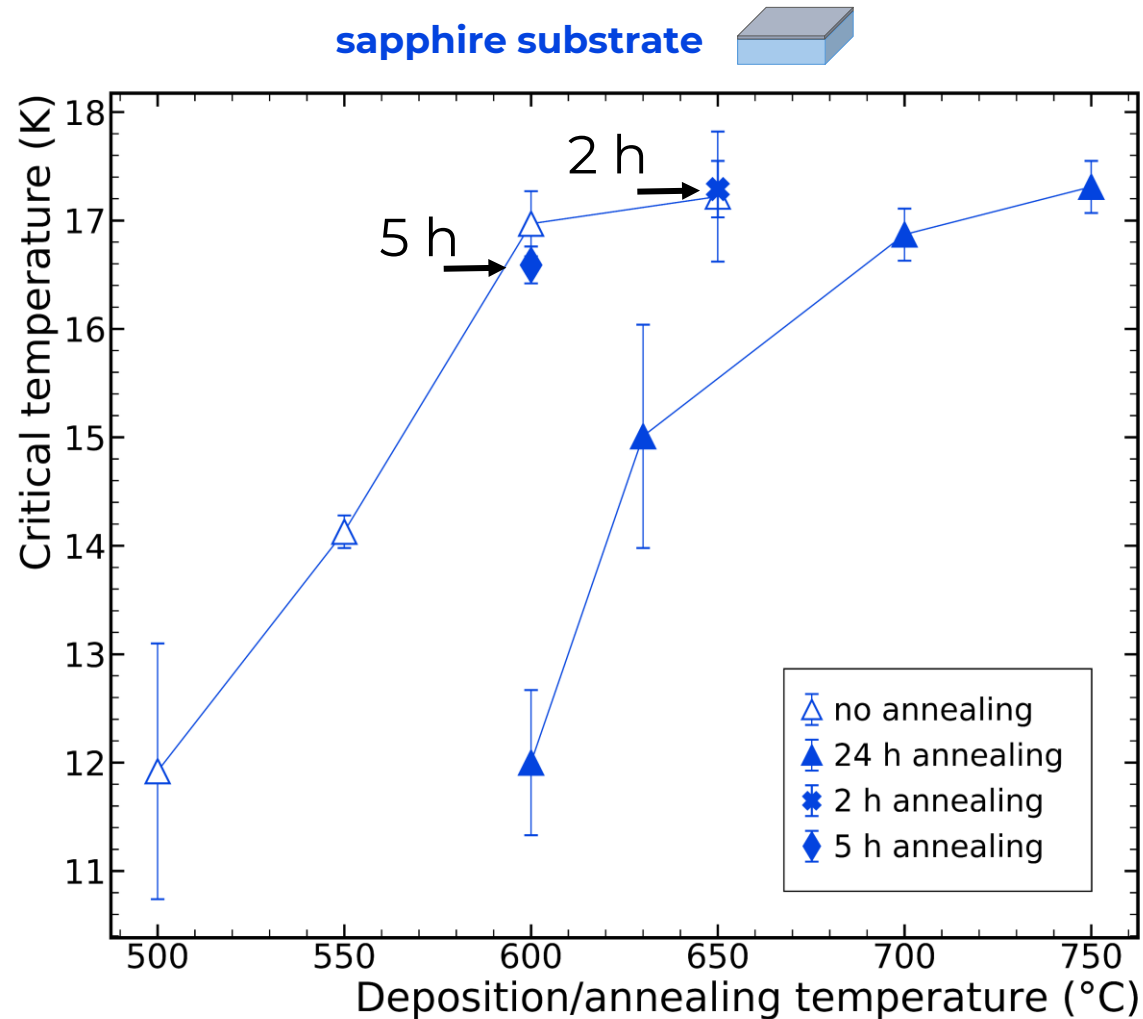


# Pressure and cathode power

Deposition temperature = 630 °C



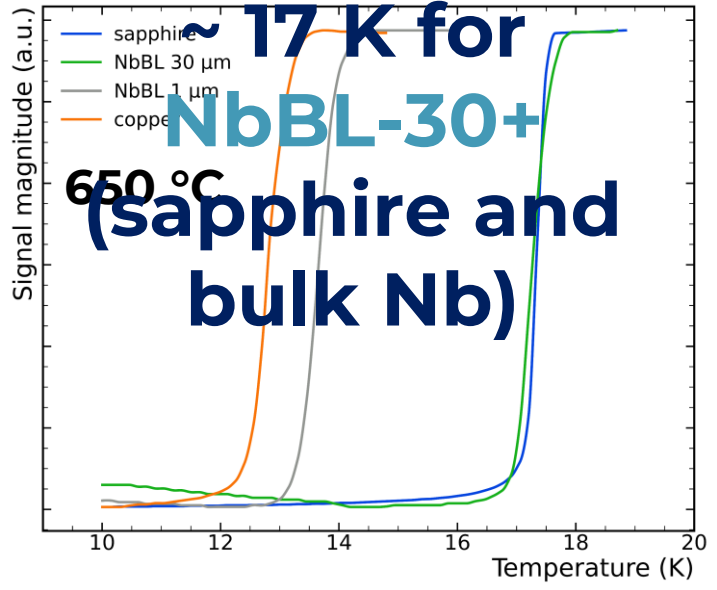
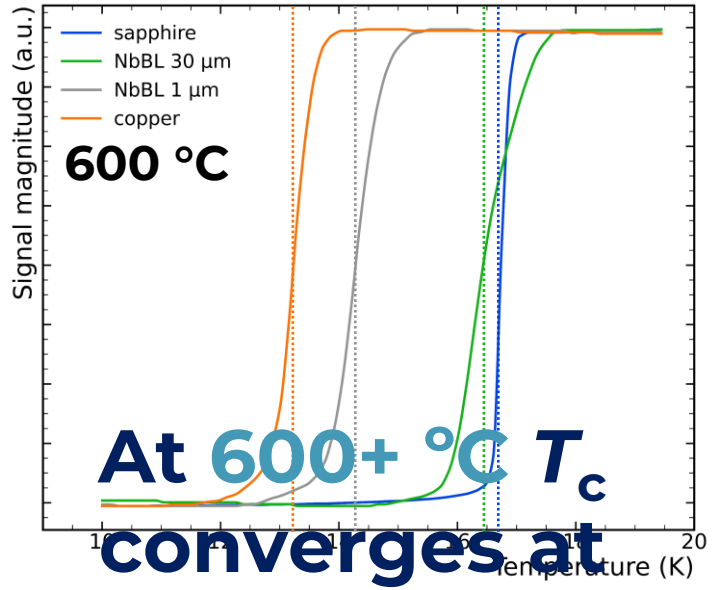
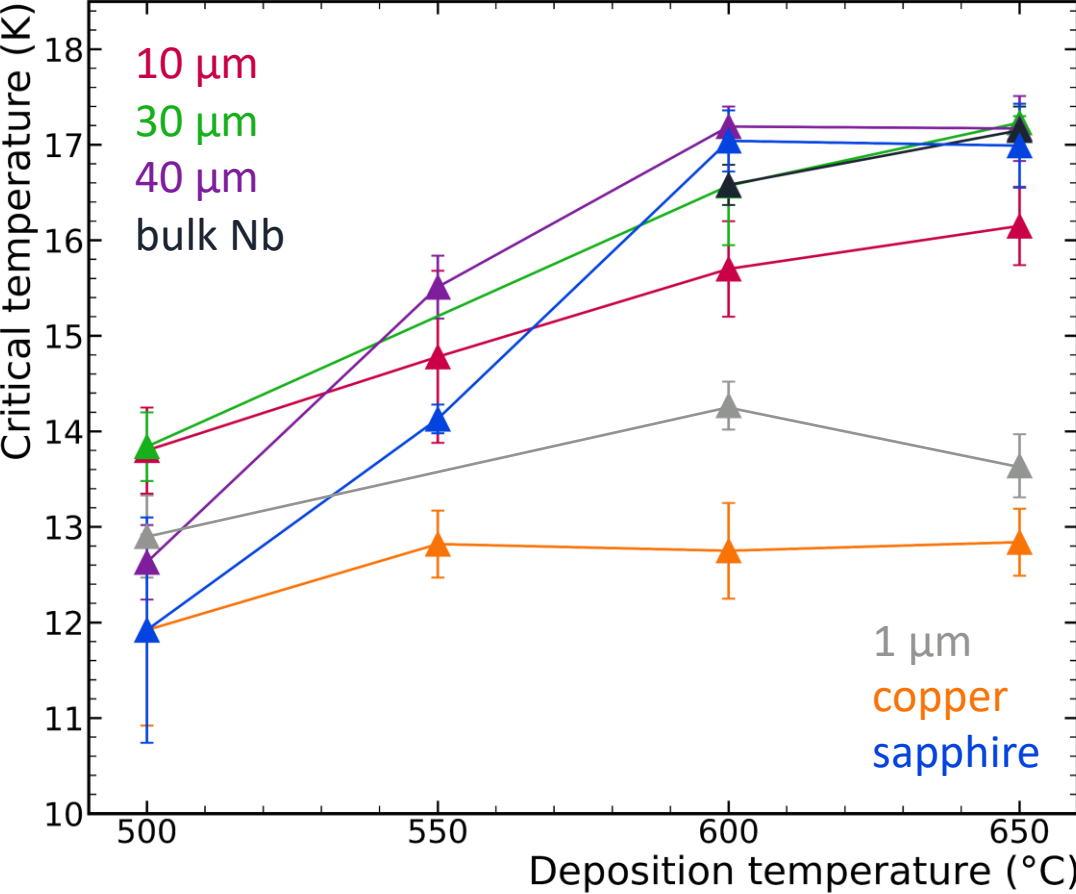
# Temperature and annealing time



**Annealing detrimental for  $T_c$**

# Role of the NbBL

## No annealing

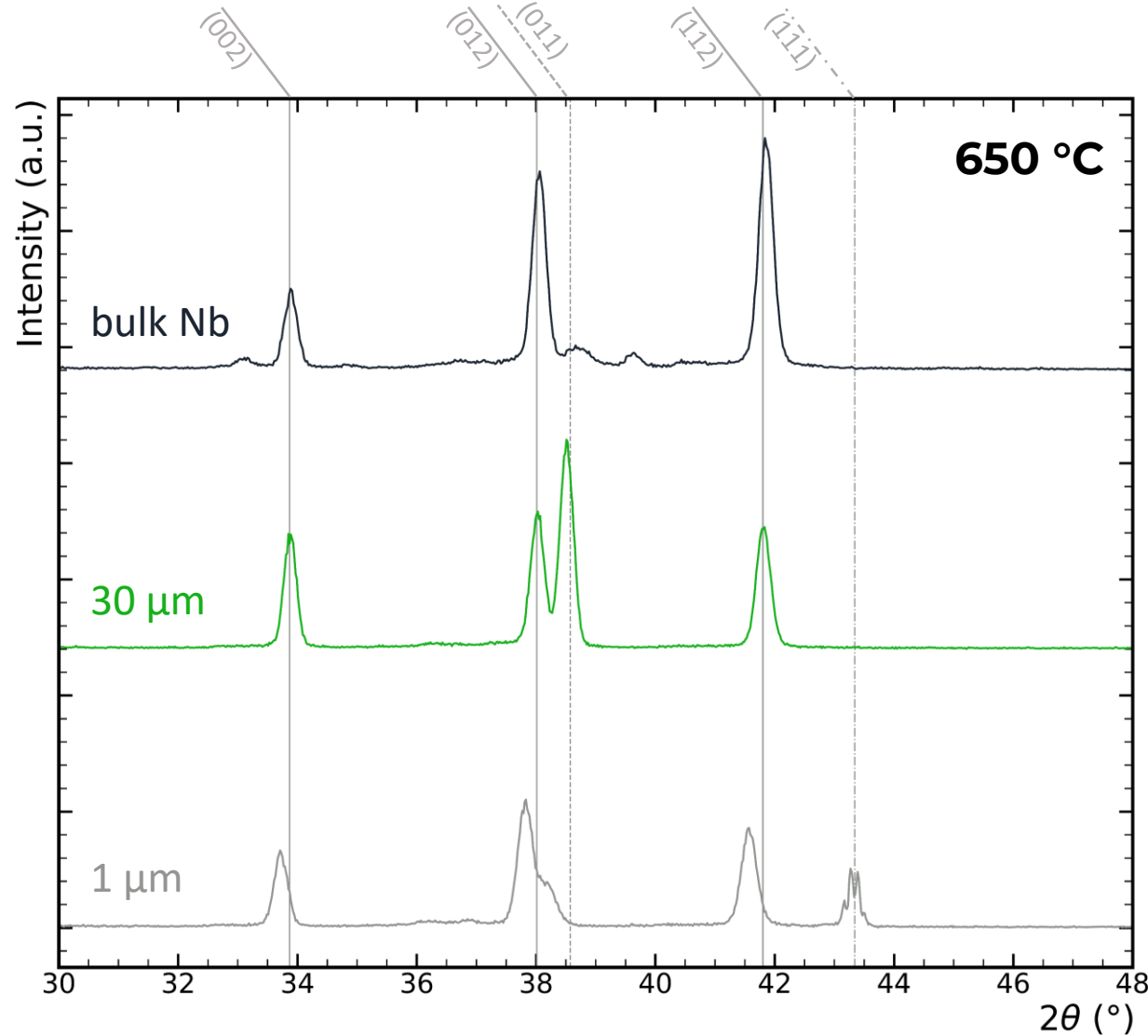


# Recap: Nb<sub>3</sub>Sn base recipe

- **Based on the observed results**
  - Low cathode power < **20 W**
  - Deposition pressure **2 x 10<sup>-2</sup> mbar**
  - **No annealing**
  - Deposition temperature **600 °C – 650 °C**
- **NbBL thickness plays a major role**

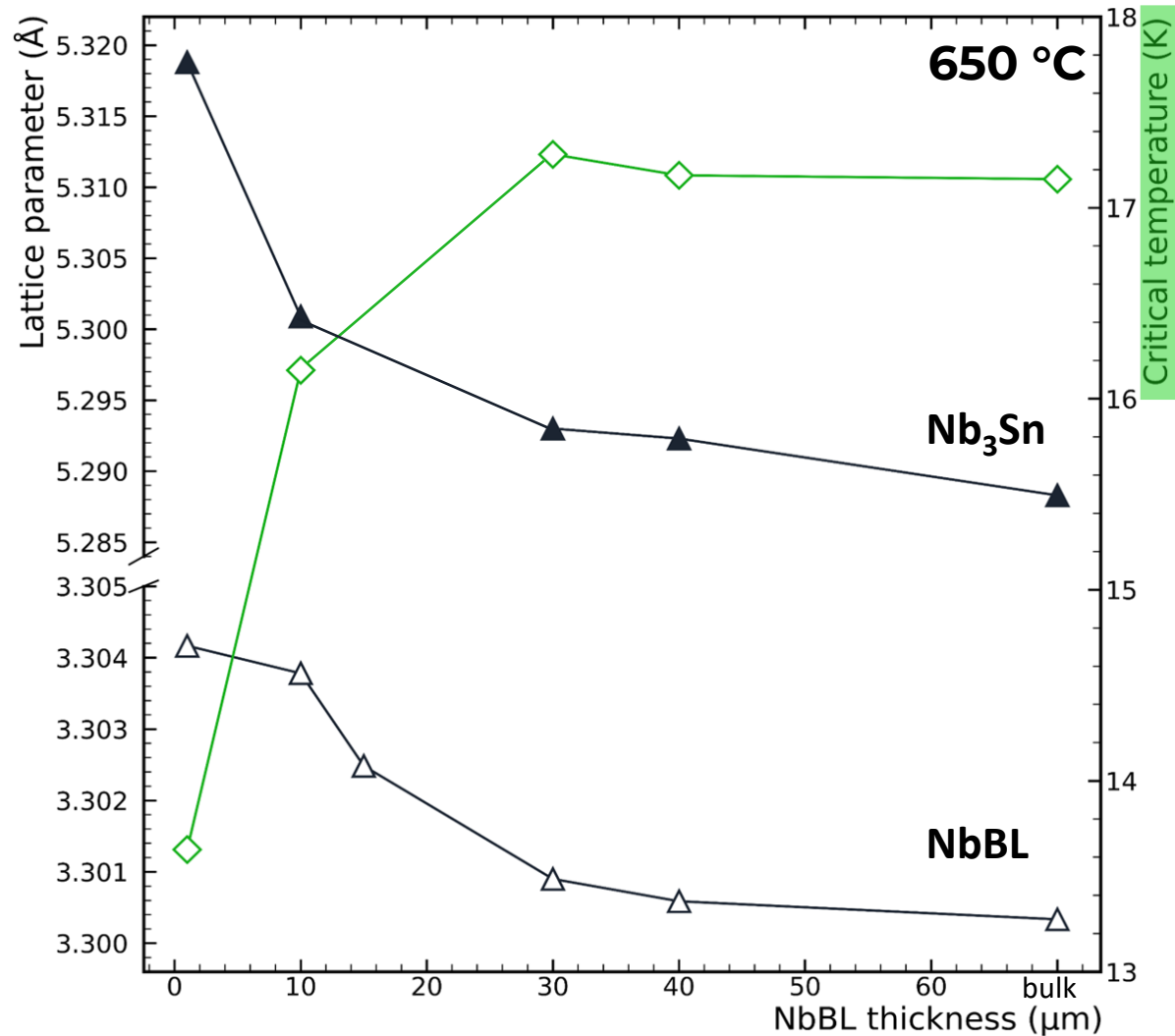
# NbBL effect on lattice parameter

X-Ray Diffraction spectroscopy (XRD)



↑  
Peaks shift  
toward  
nominal  
values

# NbBL effect: accommodation

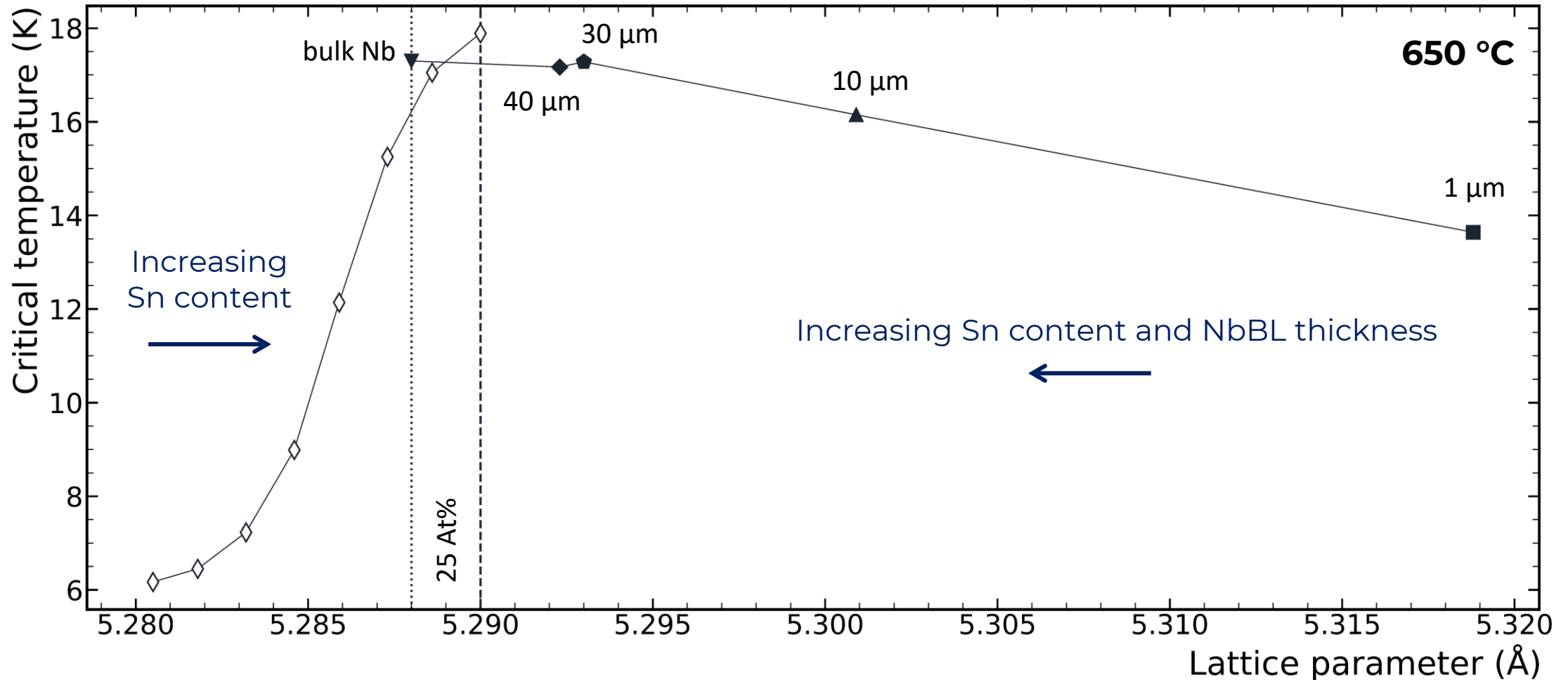


**A thicker NbBL promotes the formation of the A15 phase (see  $T_c$ )**

**30+ μm is the “saturation” thickness**

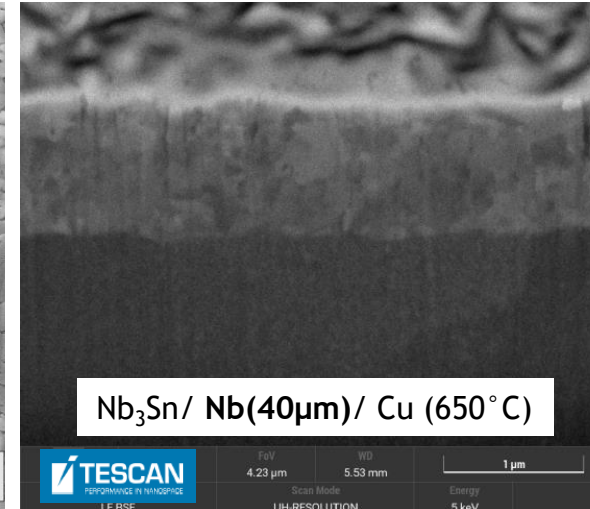
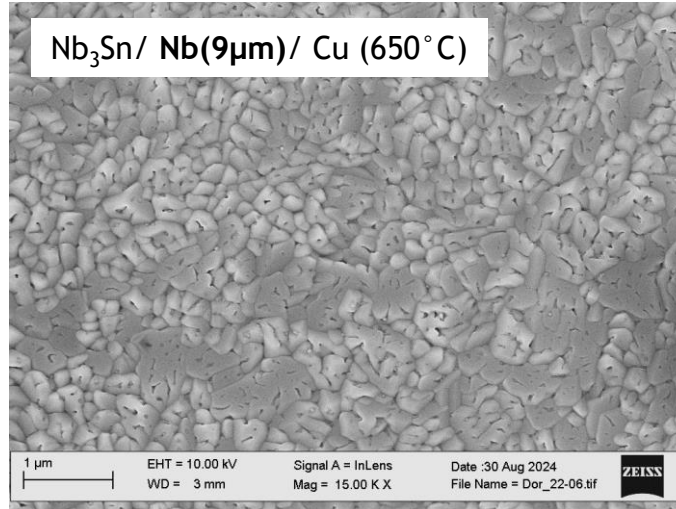
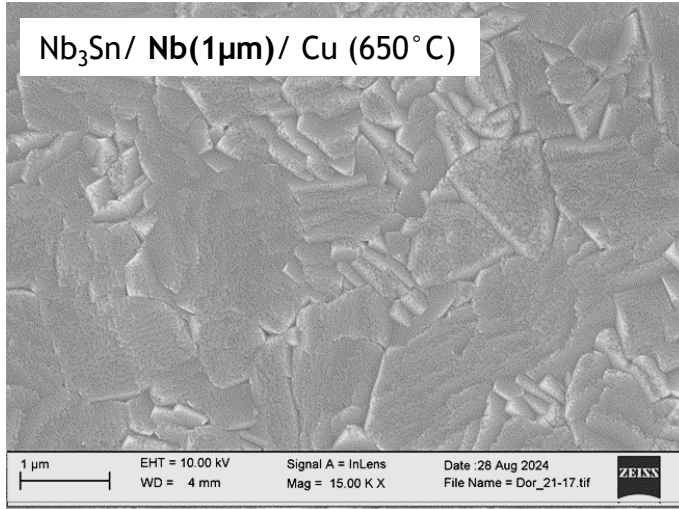
# NbBL effect: accommodation

DCMS data comparison to literature data  $\diamond$  [A Godeke 2006 *Supercond. Sci. Technol.* 19 R68]



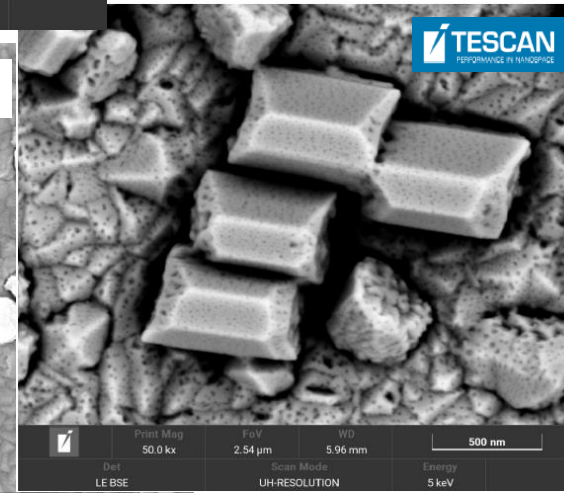
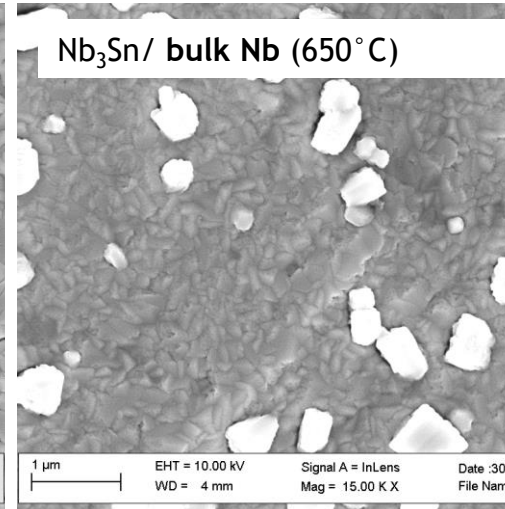
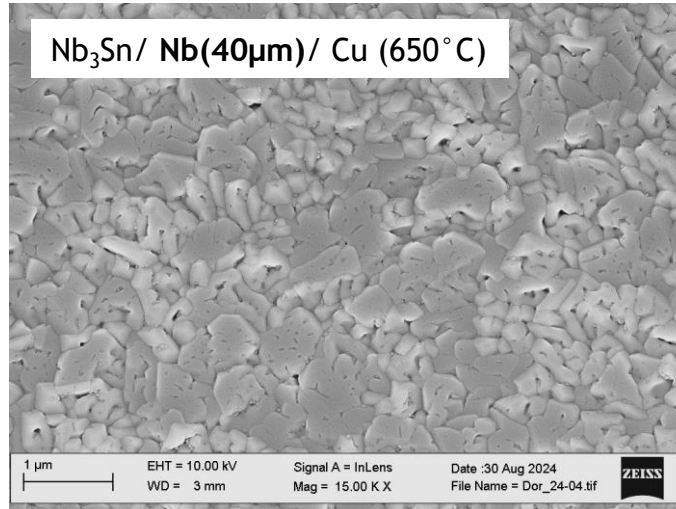
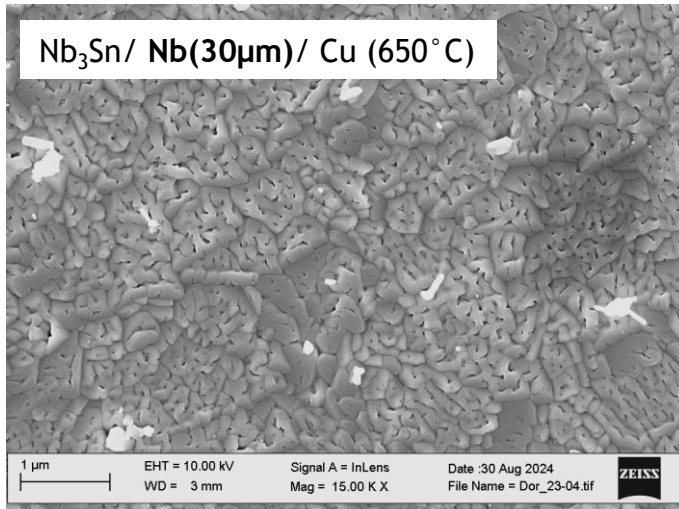


# NbBL effect: morphology



1 μm

500 nm

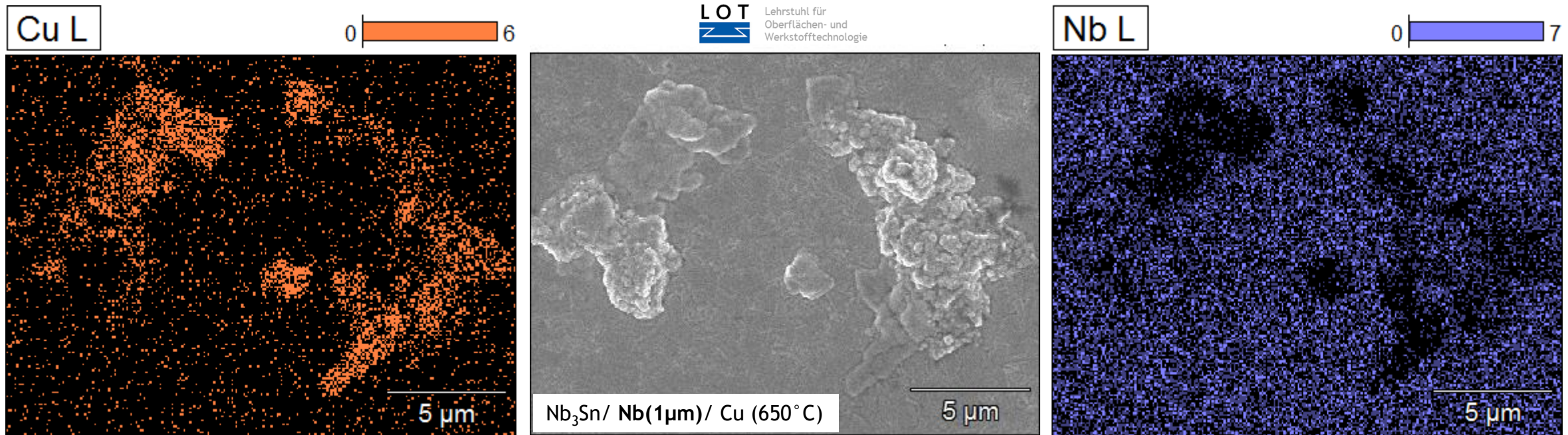


# NbBL effect: morphology

Copper inclusions on film deposited on 1  $\mu\text{m}$  NbBL



Scanning Electron Microscopy (SEM) + Energy Dispersive X-ray spectroscopy (EDX)

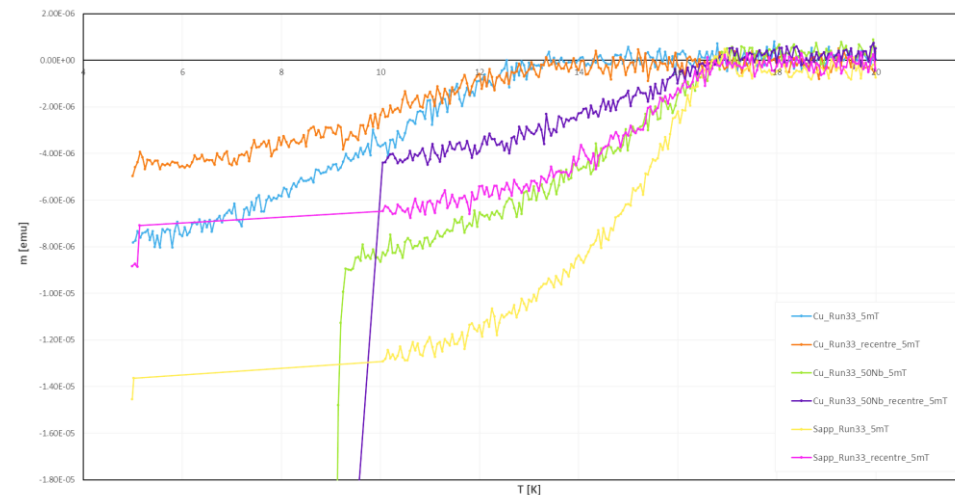
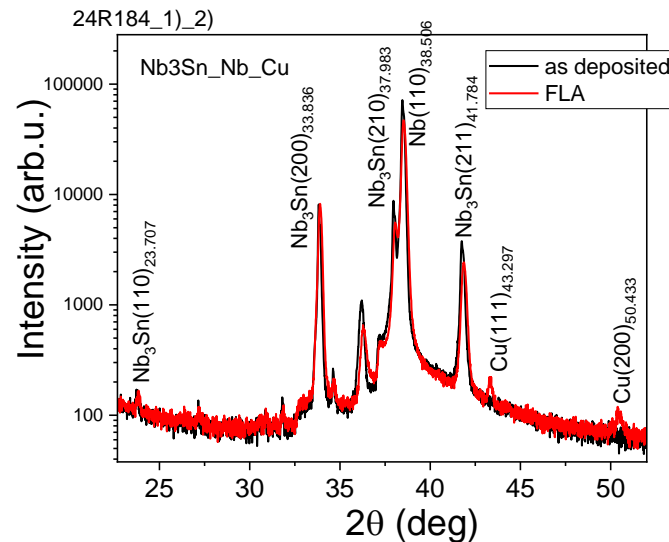


# Additional studies



- Magnetometry
- **RF surface impedance in high/low DC magnetic field**
- Superconducting gap
- Flash Lamp Annealing (FLA)
- laser treatment

**P. Vidal Garcia's talk**  
later this morning!



# 2

## RF test results

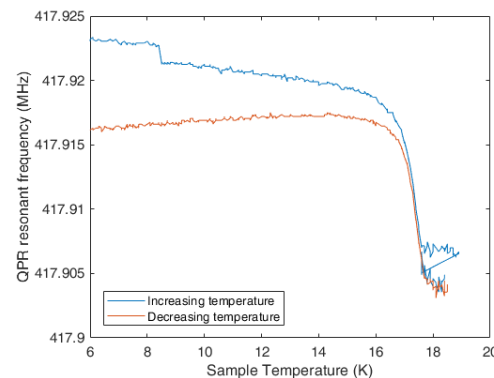
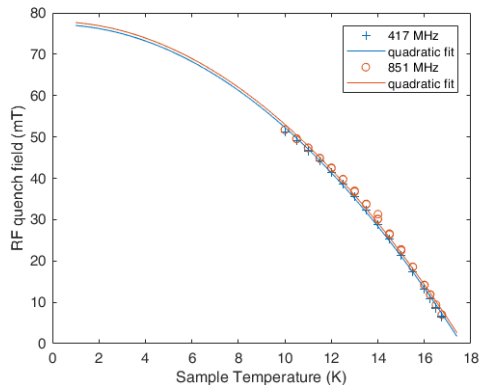
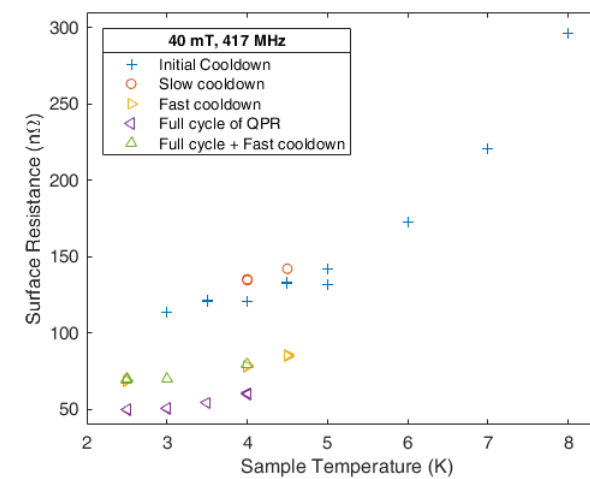
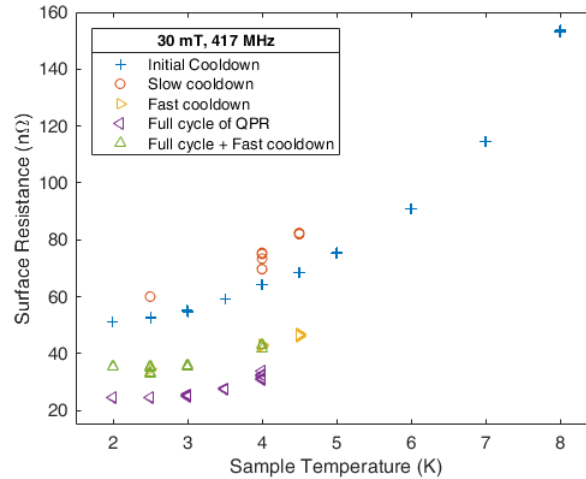
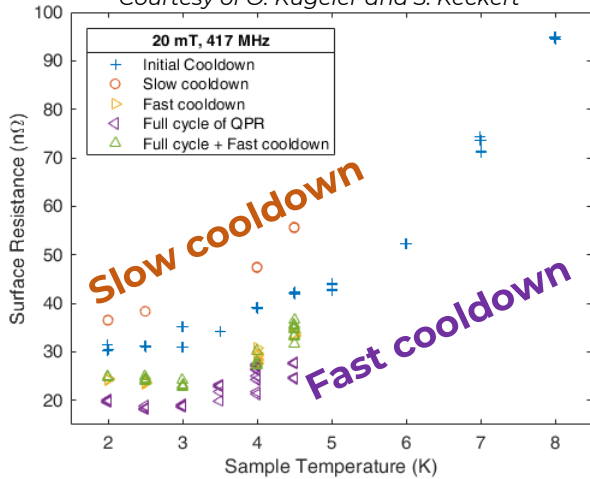
# Nb<sub>3</sub>Sn/bulk Nb QPR test

QPR = Quadrupole Resonator

**HZB** Helmholtz  
Zentrum Berlin



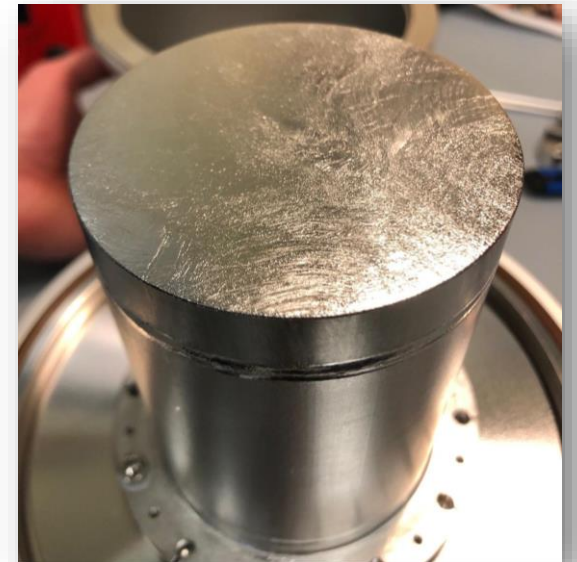
Courtesy of O. Kugeler and S. Keckert



$R_s \sim 23 \text{ n}\Omega$   
@ 4.5 K, 20 mT

Quench > 70 mT  
@ 4.5 K

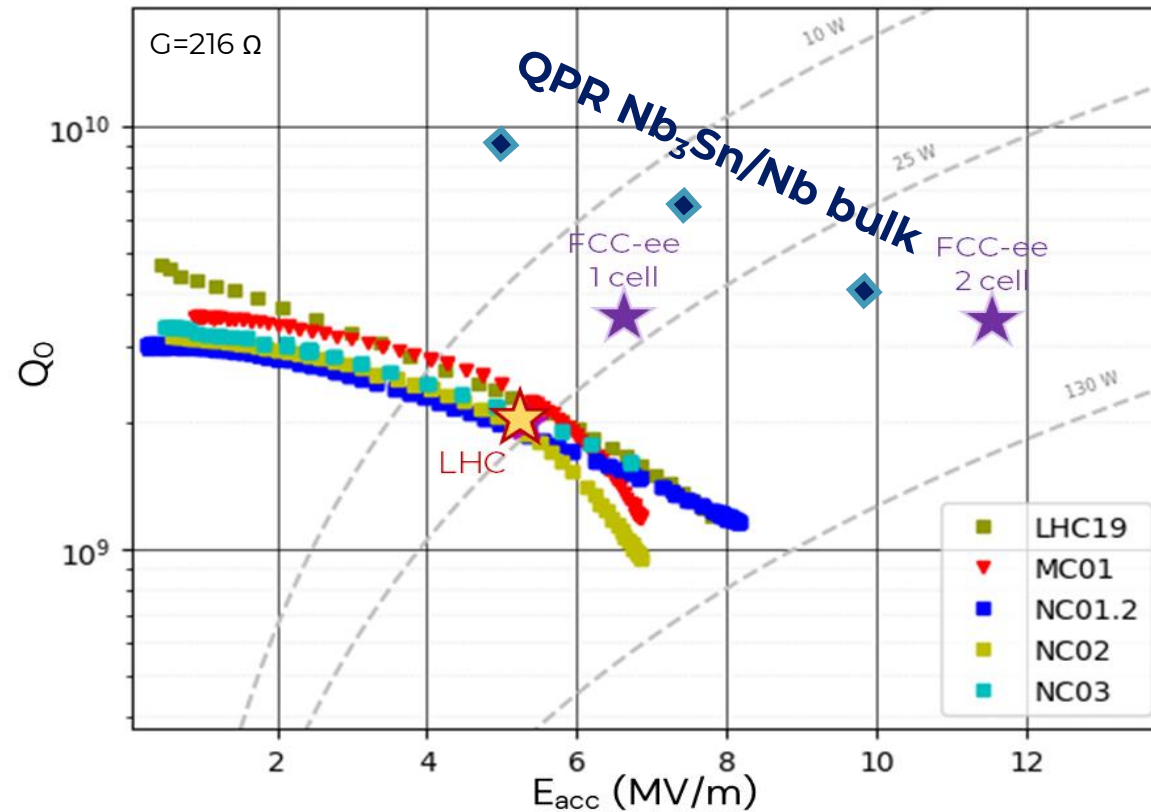
- Nb<sub>3</sub>Sn coating suffers from flux trapping
- Cooldown procedure influence  $R_s$



# Nb<sub>3</sub>Sn/bulk Nb QPR test

Comparison to LHC baseline:  $Q_0$  vs.  $E_{\text{acc}}$  @ 4.5 K

LHC cavities  
Nb/Cu 400 MHz

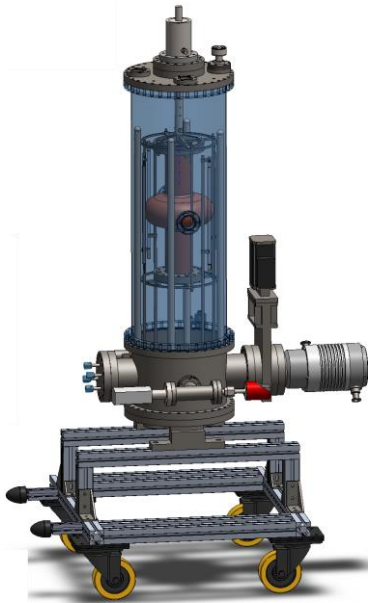


Equivalent to  
 $Q_0 \sim 9 \times 10^9$   
@ 5 MV/m  
@4.5 K

# 3

## Coating system for 1.3 GHz prototype

# Nb<sub>3</sub>Sn/Cu 1.3 GHz final prototype

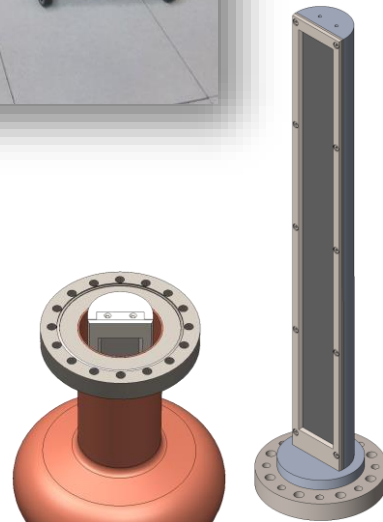


**Nb<sub>3</sub>Sn on bulk Nb to validate coating performances on 1.3 GHz Elliptical Cavities (2025)**

**Develop Nb thick barrier/accommodation layer on 1.3 GHz Elliptical Cavities (2025) (proof of concept on 6 GHz cavities already done)**

**Nb<sub>3</sub>Sn on Cu with thick Nb coating on 1.3 GHz Elliptical Cavities (2026-2028)**

- 1.3 GHz vacuum system ready
- Magnetron source **commissioned**



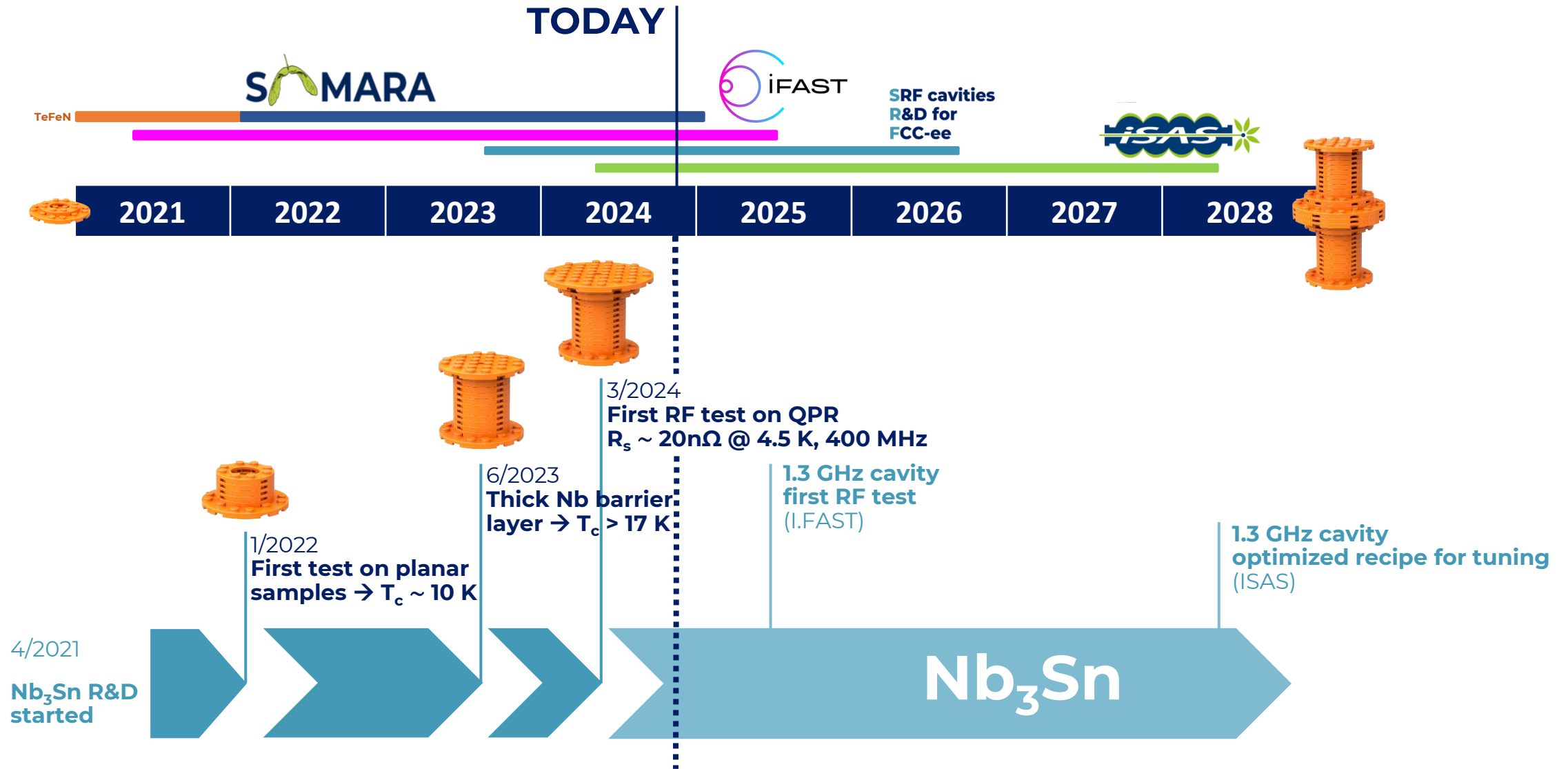
In parallel:

- Study on alternative buffer layer
- Study on flux trapping





# Timeline



# Conclusion

- the optimization of **Nb<sub>3</sub>Sn deposition recipe via DCMS** is at an advanced stage on small samples
  - **$T_c \sim 17.5$  K**
  - deposition temperature **600 °C - 650 °C**
  - thickness of **NbBL 30+ μm** → accommodation effect
- first RF test for film deposited on **bulk Nb on QPR sample**: promising  **$R_s \sim 23$  nΩ** @ 4.5 K, 20 mT
- parallel work on **coating system for 1.3 GHz** with rectangular magnetron

# Thank you!



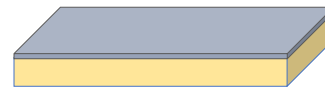
# Standard production process

## (1) Set parameters:

Cathode power  $P$   
Deposition pressure  $p_{\text{dep}}$   
Deposition temperature  
 $T_{\text{dep}}$



## (2) 1 $\mu\text{m}$ $\text{Nb}_3\text{Sn}$



Sapp  
hire



Cu + 1  $\mu\text{m}$  Nb buffer  
layer (BL)



C  
u

+ 24 h  
annealing



## (3) Characterisation:

$T_c$  measurement  
SEM + EDS (Sn  
composition)  
XRD



**Tune next parameters  
based on trends (step 1)**

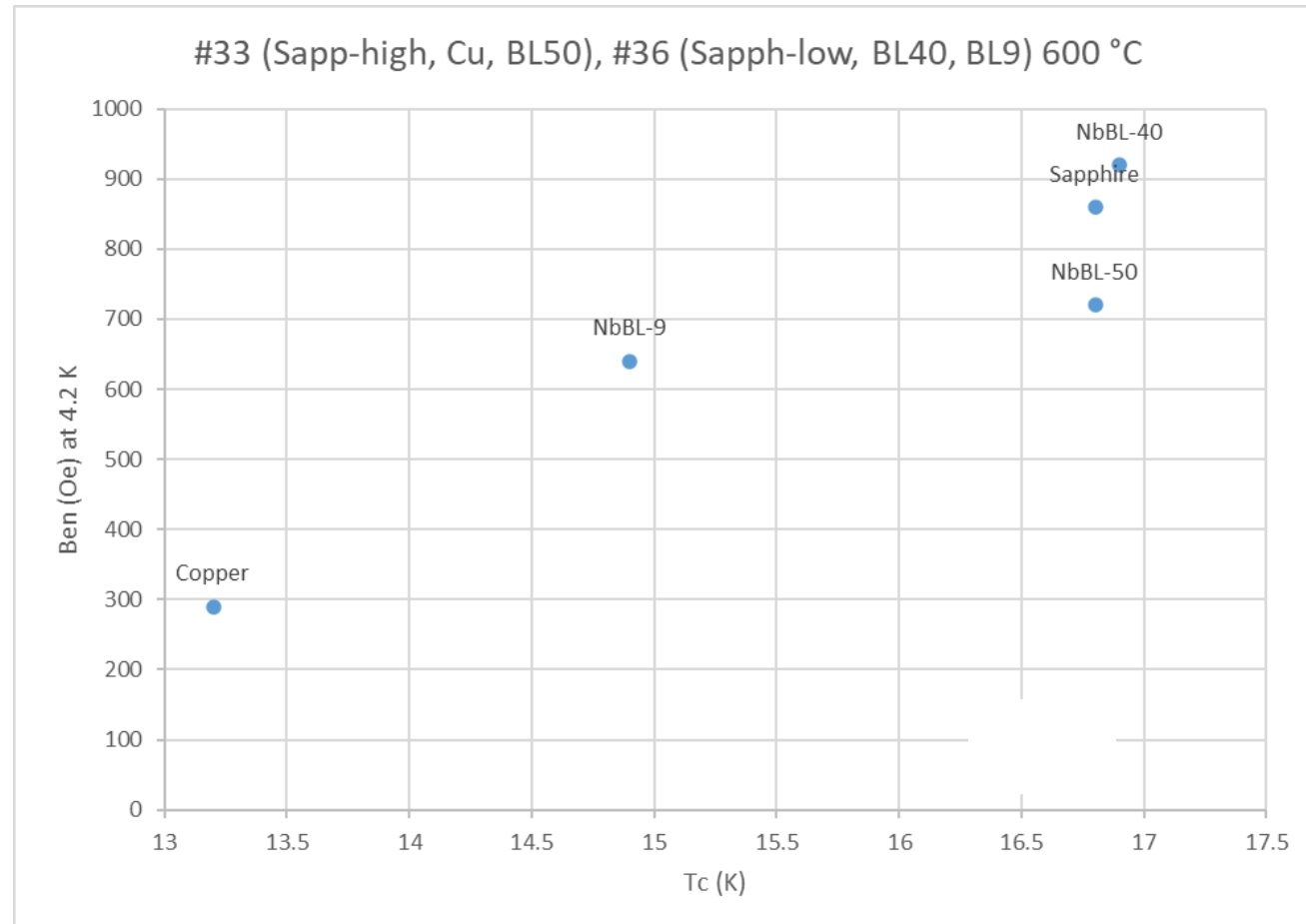
small  
samples  
on holder  
plate



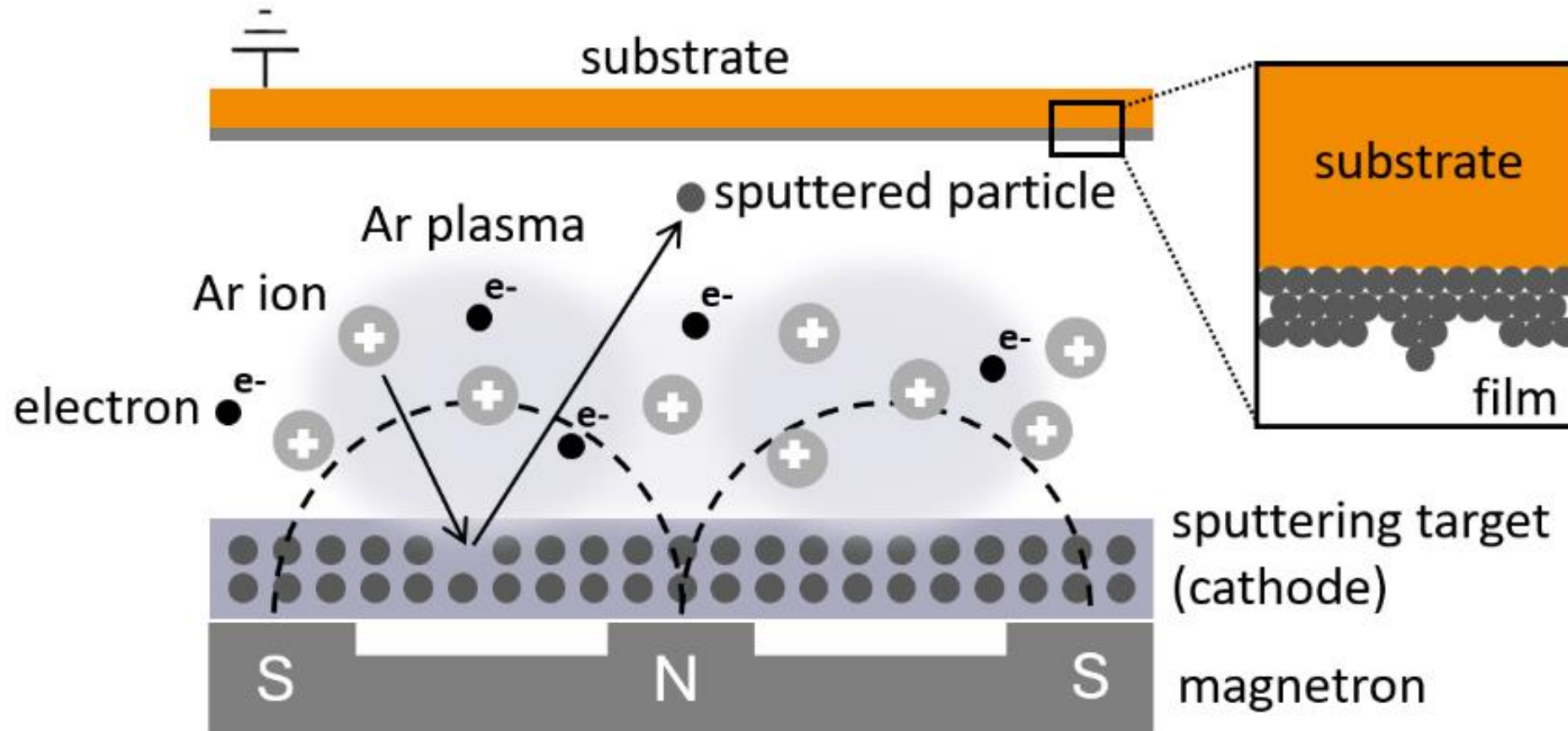
10  
cm

# Film properties

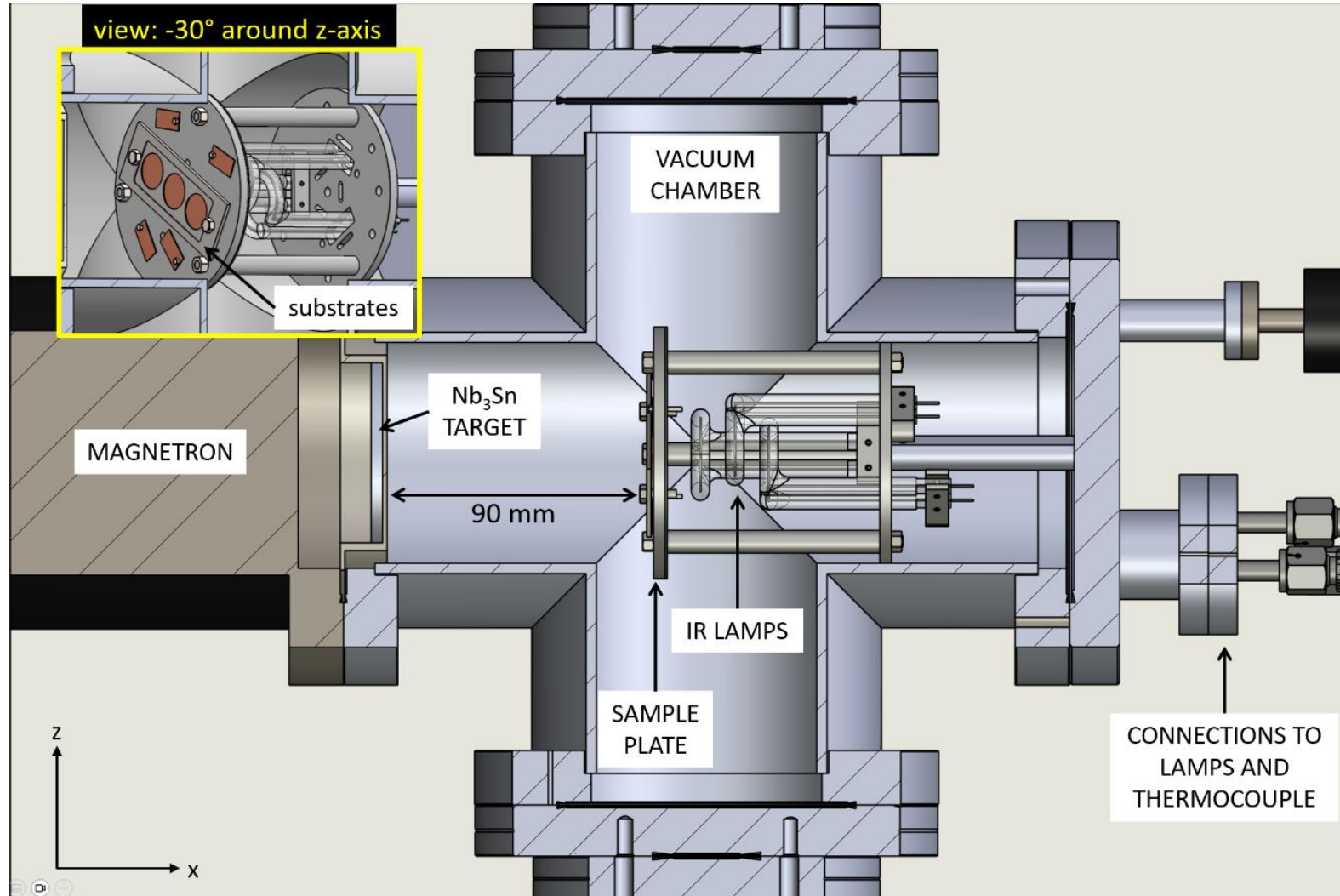
## Field of first flux entry $B_{en}$



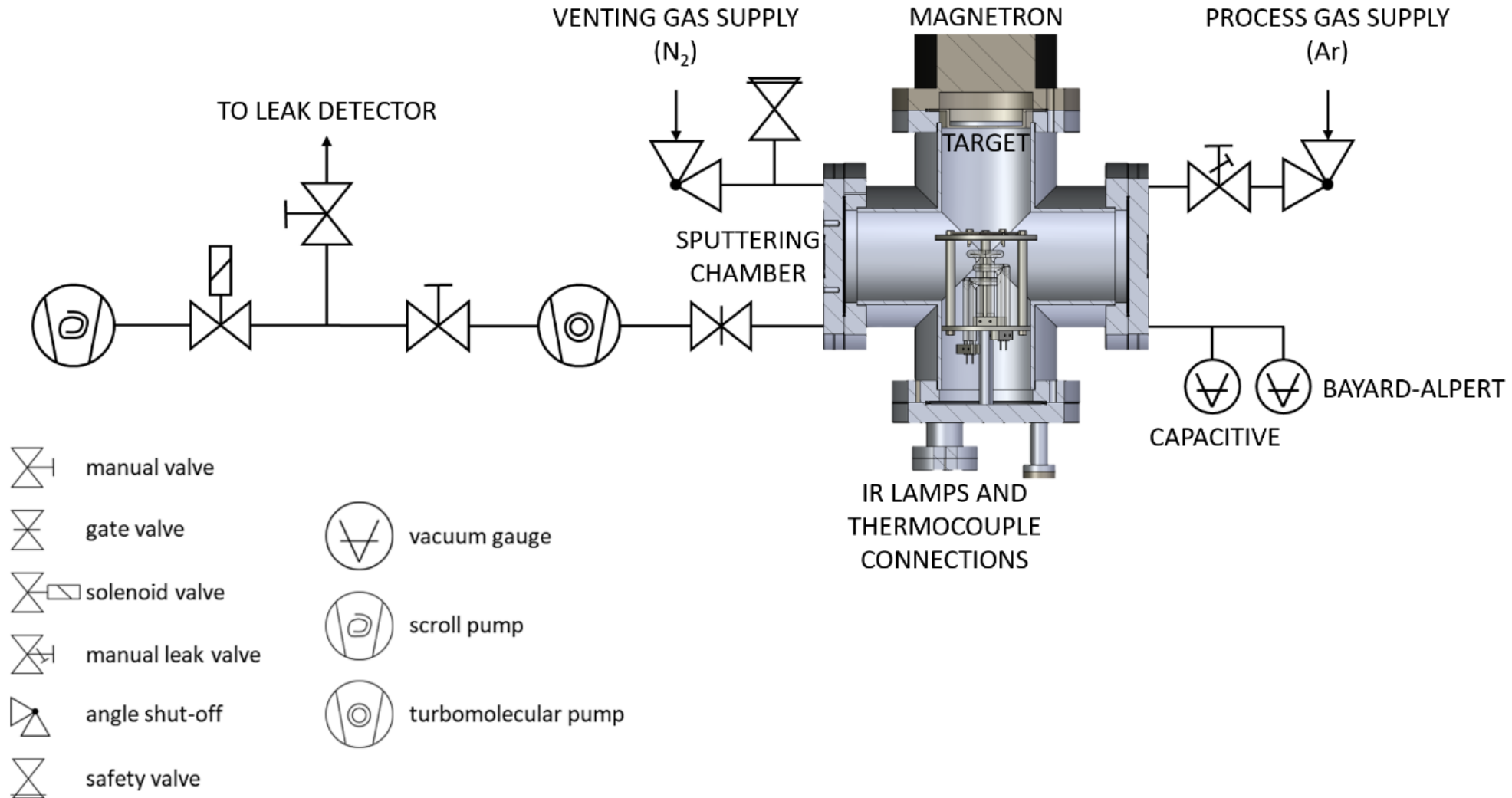
# DC Magnetron Sputtering



# Nb<sub>3</sub>Sn deposition system



# Nb<sub>3</sub>Sn deposition system





## Projects and partners:

- SAMARA (INFN CSN5)
  - INFN – LNL, INFN – TO, PoliT0, INFN – Roma3, INFN – LNF, Uni Roma 3, INFN – MI, INFN – LASA
- I.FAST WP9 (EU's Horizon 2020 Research and Innovation programme GA101004730)
  - IEE – SAS, RTU, Piccoli S.R.L., Uni Siegen, LOT, HZB, HZDR, CEA, IJC, UKRI, Uni Lancaster, Uni Liverpool, UniPD; INFORMAL: CERN, DESY; ASSOCIATED: JLab
- SRF (INFN Board for FCC R&D)
- ISAS (EU's Horizon Europe Research and Innovation programme GA101131435)
  - IEE – SAS, RTU, Piccoli S.R.L., Uni Siegen, LOT, HZB, HZDR, CEA, IJC, UKRI, Uni Lancaster, Uni Liverpool, UniPD, CERN, DESY, JLab, Fermilab
- SuperMAD (INFN CSN5)
  - INFN – LNL, INFN – TO, PoliT0, INFN – Roma3, INFN – LNF, Uni Roma 3, ENEA